

**UCF MATERIALS CHARACTERIZATION  
FACILITY CORPORATE FEE SCHEDULE  
2024-2025**

<b><u>Equipment</u></b>	<b><u>Hourly Rate</u></b>
<b>Scanning Electron Microscopy (SEM)</b>	
Jeol JSM-6480	150
Zeiss Ultra-55	200
<b>Transmission Electron Microscopy (TEM)</b>	
Jeol JEM-1-11	300
Tecnaï F30	450
<b>Focused Ion Beam (FIB)</b>	
FEI 200 TEM	250
Zeiss FIB Crossbeam	350
<b>X-Ray Diffraction (XRD)</b>	
XRD -- GN (Panalytical)	150
XRD -- TF (Panalytical)	200
XRD -- EC (Panalytical)	200
<b>Secondary Ion Mass Spectrometry (SIMS)</b>	
Cameca IMS-3F	300
PHI Adept	300
<b>Miscellaneous</b>	
XPS Escalab 250Xi	300
X-Ray Fluorescence Spectrometer (XRF) (Panalytical)	150
Sputter Coater (Quoram)	150
<b>Other Instruments</b>	
Metal Polisher Allied	50
Critical Point Dryer	50
Diamond Wafering	50
Dimple Grinder	50
PECS Gatan (Coating System)	75
Ion Milling	100
Ultra Microtom (Leica)	100
Leica Trimmer	75
Plasma Cleaner	50
Confocal Laser Scanning Microscope	100
Metallurgical Microscope	80
MicroRaman Spectroscopy	100
Profilometer	150
Reichert Optical Microscope	100